

CLAIMS

1. A ceramic substrate having a conductor layer formed inside thereof or on the surface thereof,
wherein a notch is formed.
2. The ceramic substrate according to claim 1,
which has a resistance heating element formed inside thereof or on the surface thereof; and functions as a hot plate.
3. The ceramic substrate according to claim 1,
which has an electrostatic electrode formed inside thereof; and functions as an electrostatic chuck.
4. The ceramic substrate according to claim 1,
which has a chuck top conductor layer formed on the surface thereof; has a guard electrode and/or a ground electrode formed inside thereof; and functions as a wafer prober.